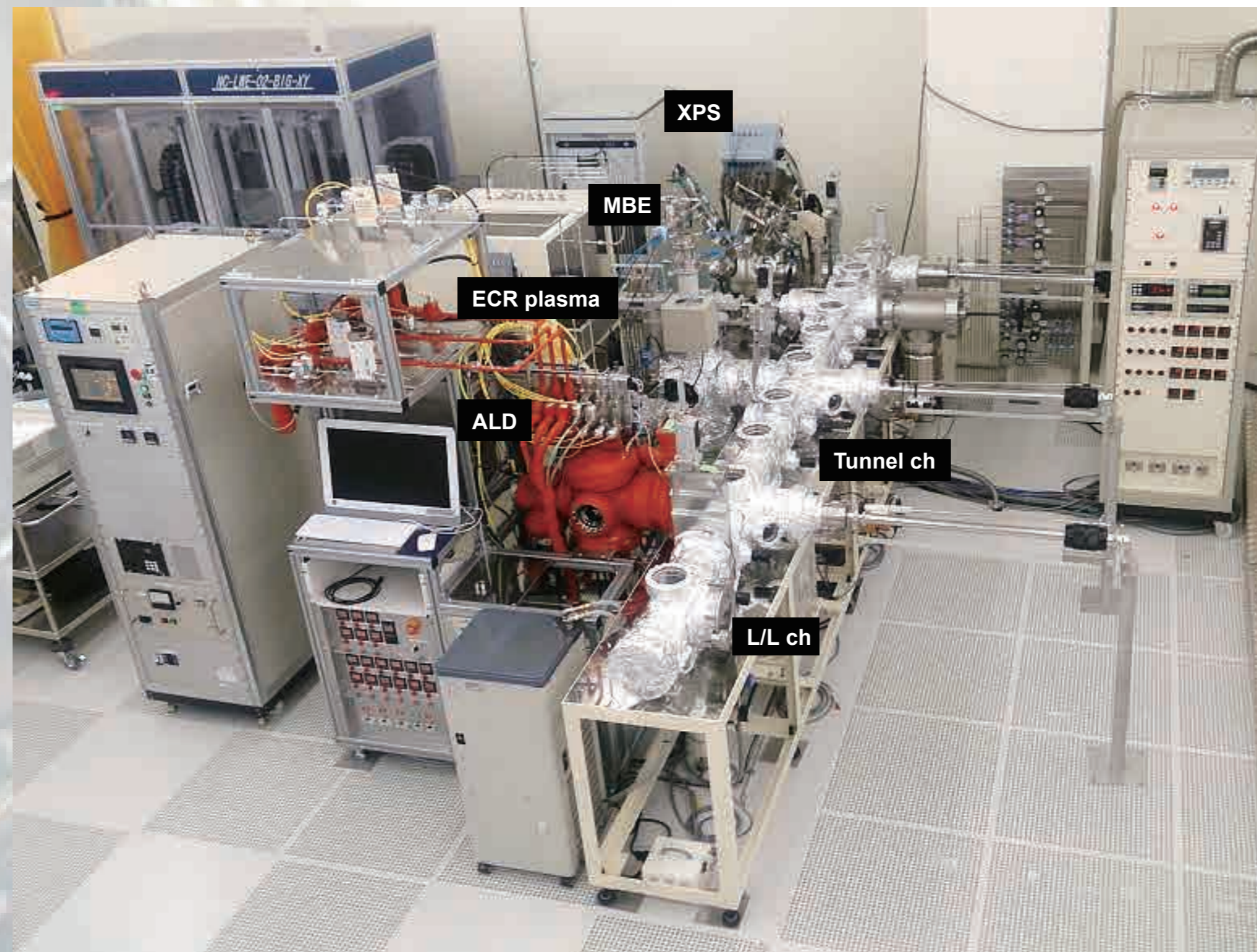
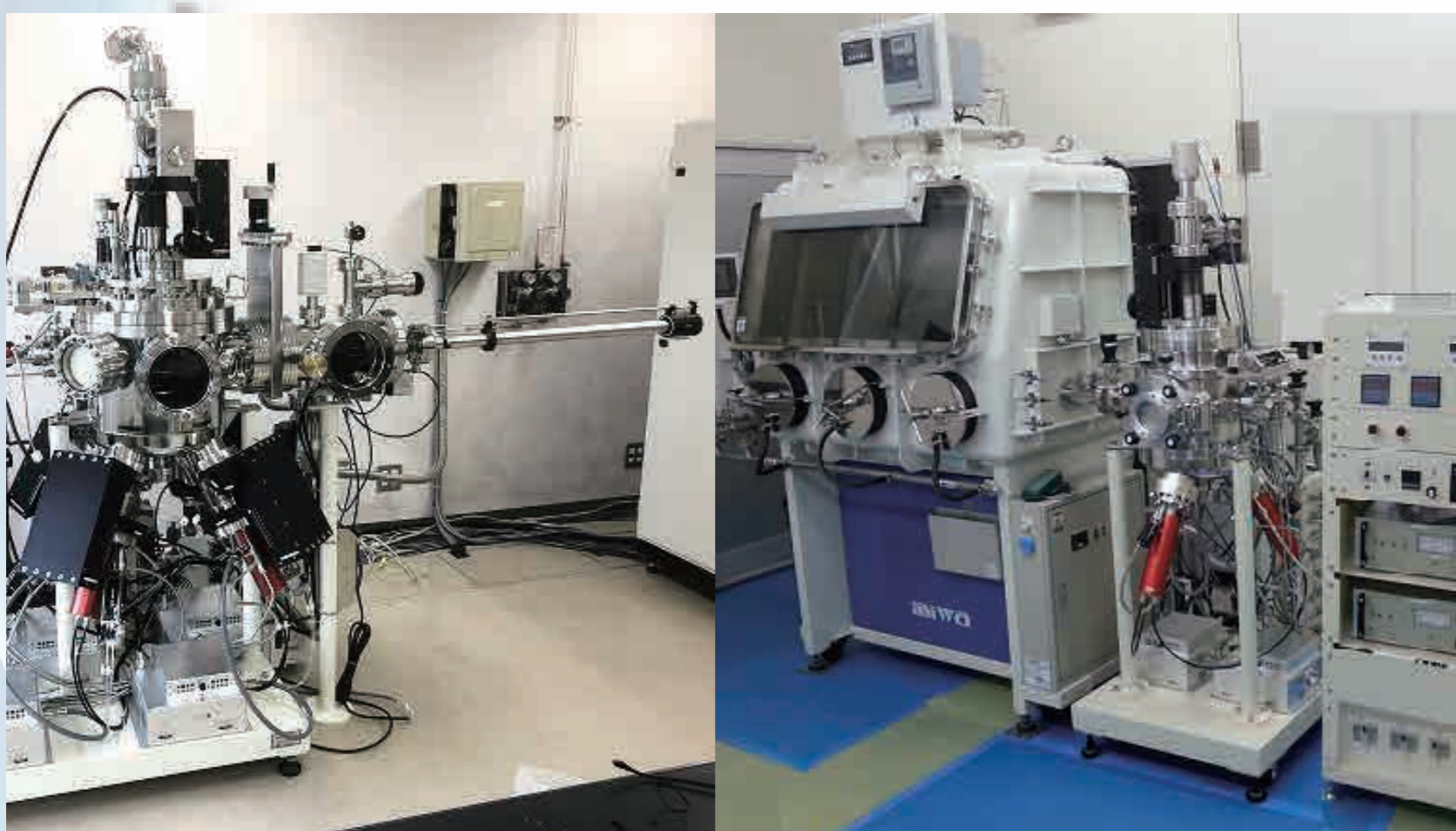


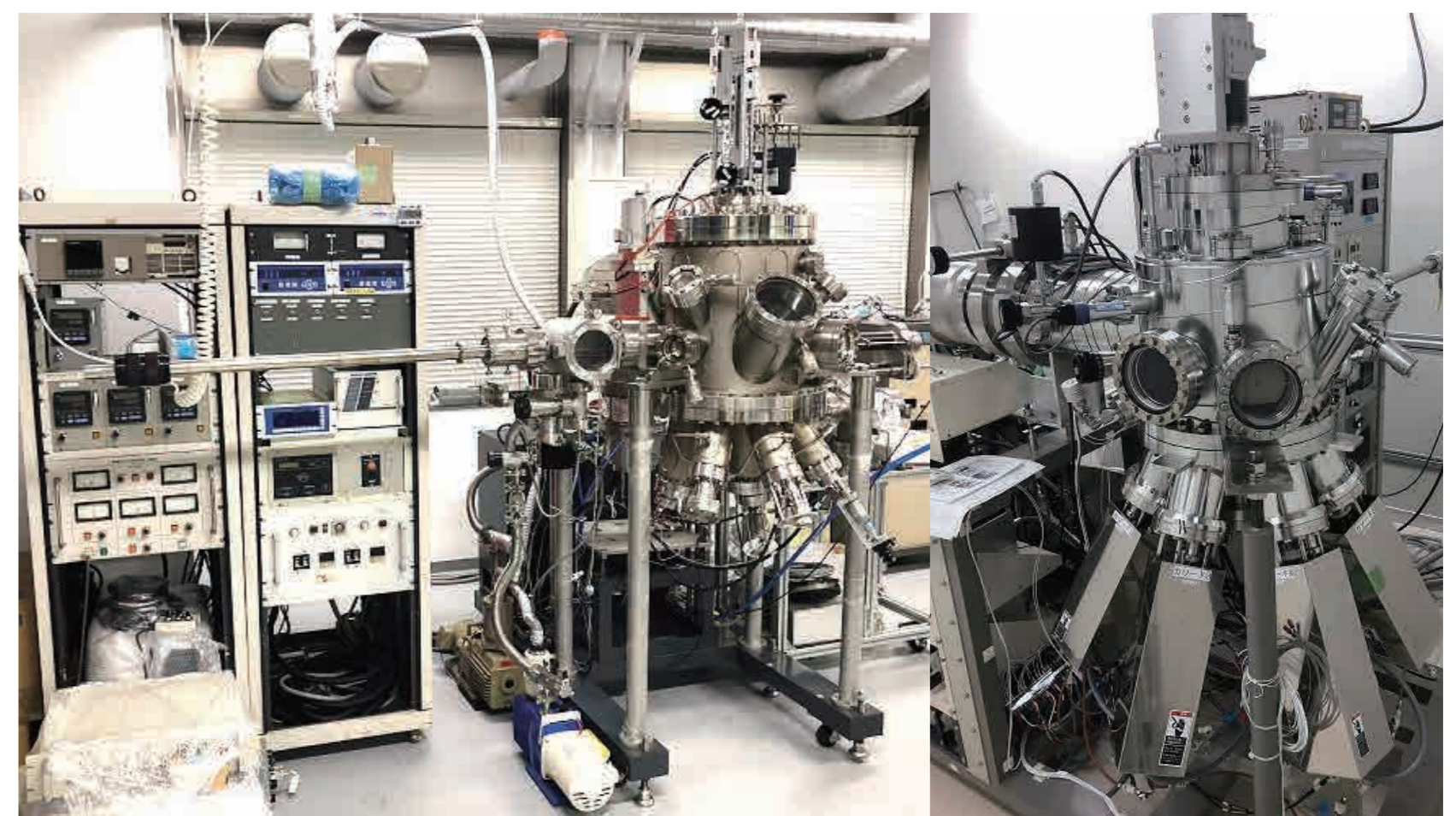
High-performance thin film production system



Vacuum integrated deposition and evaluation system



UHV Sputtering Sputtering with Globe-box



MBE



3-pockets EB evaporation Single pocket EB & sputtering



Evaporation with Globe-box



TEOS Plasma CVD

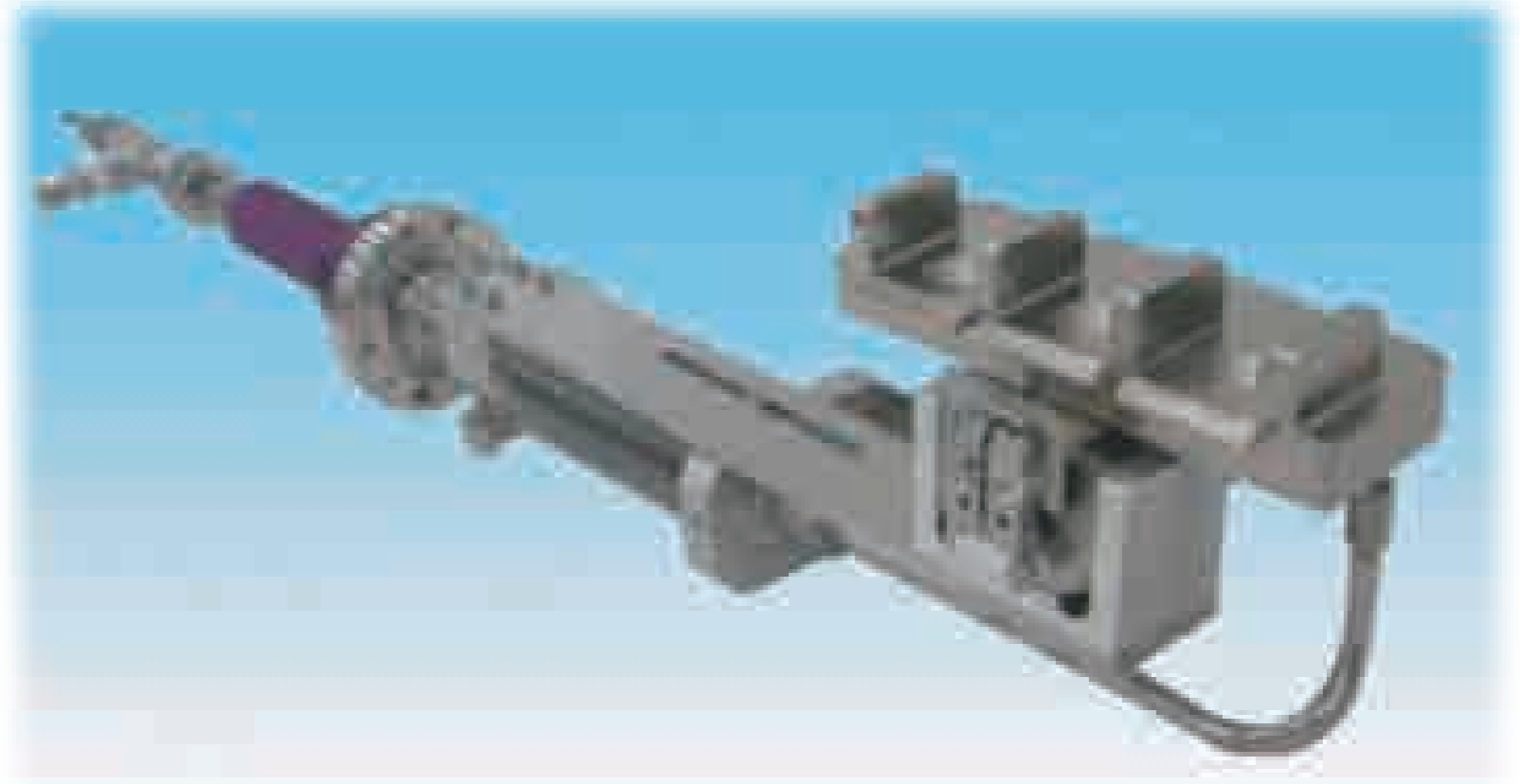


Vertical MO-CVD

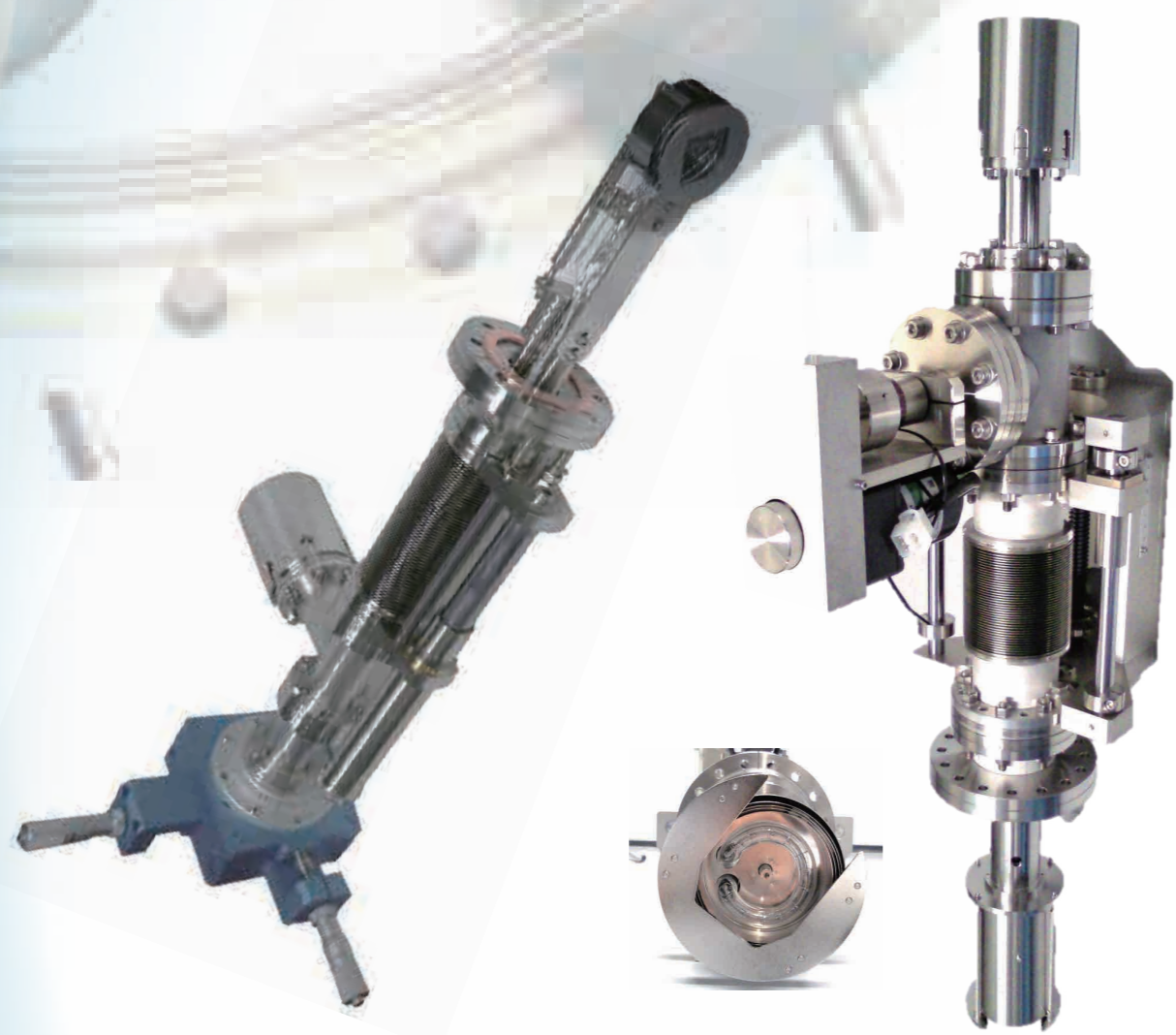
Thin film production components



Sputtering Cathode



3-pockets EB evaporator



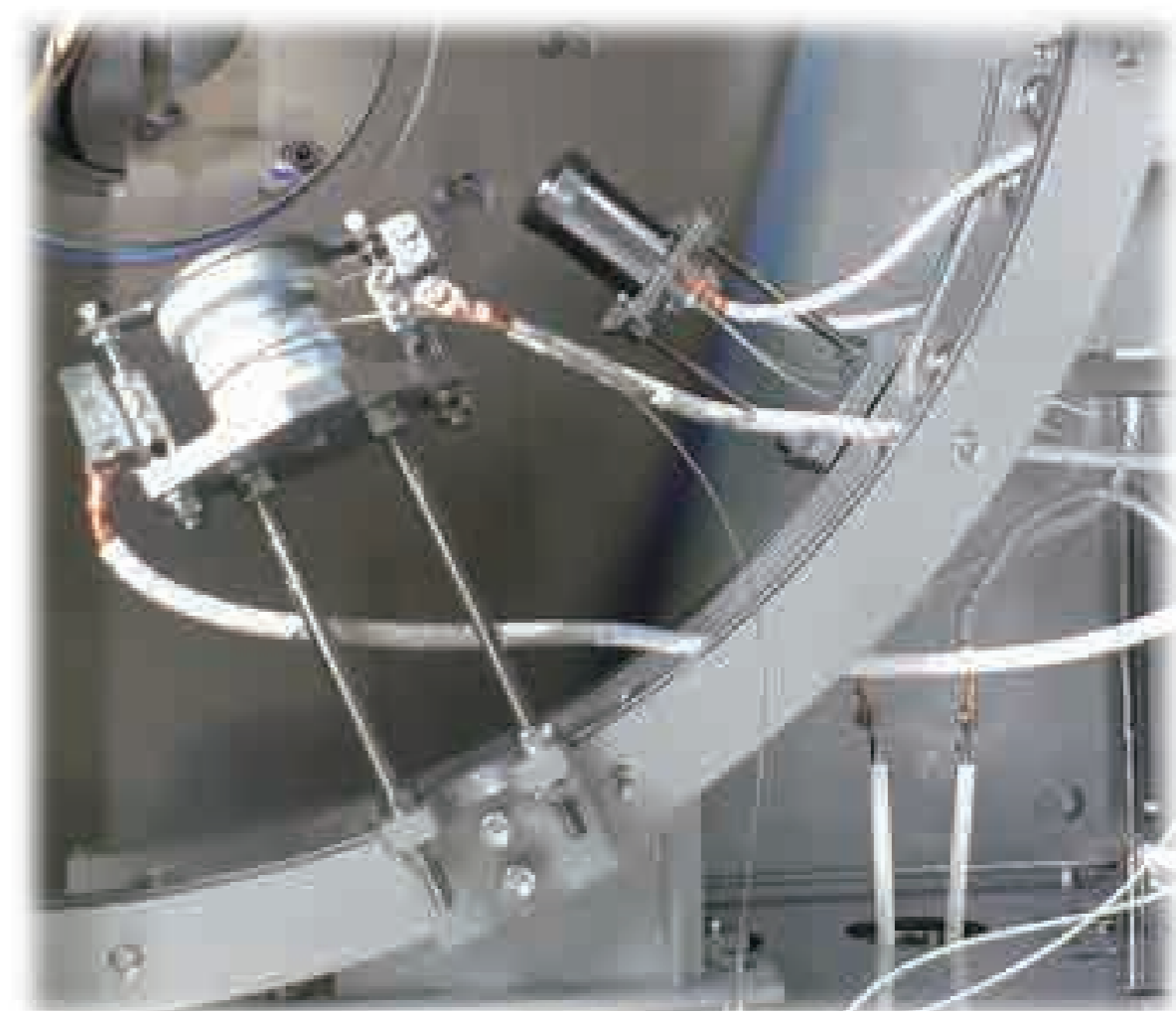
Manipulator



Standard & High-Temp K-cell



High vapor pressure K-cell



Simple evaporation source Metal & Organic



Resistance heating evaporation source



Plasma source with heating